



2874

PATENT

Docket No.: 176/60921 (2-11150-912)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Lukas Novotny and Thomas G. Brown )  
Serial No. : 10/068,449 )  
Cnfrm. No. : 9533 )  
Filed : February 7, 2002 )  
For : A SYSTEM AND METHOD FOR HIGH )  
RESOLUTION OPTICAL IMAGING, DATA )  
STORAGE, LITHOGRAPHY, AND )  
INSPECTION )

Examiner:  
Pearlene Foster

Art Unit:

2823  
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JUN 26 2003

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SECOND SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT  
UNDER 37 CFR §§ 1.97-1.98

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Dear Sir:

Pursuant to 37 CFR §§ 1.97-1.98, applicants hereby bring to the attention of the  
United States Patent and Trademark Office, the enclosed references listed on the attached  
PTO-1449 form.

Respectfully submitted,

Date: June 23, 2003

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I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450, on the date below.	
Date <u>6/23/03</u>	<u>Sherri A. Moscato</u> Sherri A. Moscato

U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE  INFORMATION DISCLOSURE STATEMENT BY APPLICANT  (use several sheets if necessary)  (PTO-1449 JUN 25 2003)	ATTY. DOCKET NO.	SERIAL NO.
	176/60921 (2-11150-912)	10/068,449
	APPLICANT Lukas Novotny and Thomas G. Brown	
	FILING DATE	GROUP ART UNIT
	February 7, 2002	2874

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPRO- PRIATE
	1	5,881,042	03/09/1999	Knight			
	2	5,936,928	08/10/1999	Jain et al.			
	3	5,963,532	10/05/1999	Hajjar			
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	9	6,324,141	11/27/2001	Takishima et al.			
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		17	Pohl et al., "Optical Stethoscopy: Image Recording With Resolution $\lambda 20$ ," <u>Appl. Phys. Lett.</u> 44:651-653 (1984)
		18	Lewis et al., "Development of a 500 Å Resolution Light Microscope," <u>Ultramicroscopy</u> 13:227-231 (1984)
EXAMINER			DATE CONSIDERED
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.			

U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT JUN 25 2003 (use several sheets if necessary) (PTO-1449)	ATTY. DOCKET NO. 176/60921 (2-11150-912)	SERIAL NO. 10/068,449
	APPLICANT Lukas Novotny and Thomas G. Brown	
	FILING DATE February 7, 2002	GROUP ART UNIT 2874

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPRO- PRIATE

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		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRAN- SLATION IF APPRO- PRIATE

## OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, Etc.)

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		20	Smolyaninov et al., "Near-field Direct-write Ultraviolet Lithography and Shear Force Microscopic Studies of the Lithographic Process," <u>Appl. Phys. Lett.</u> 67:3859-3861 (1995)
		21	Davy et al., "Near-field Optics: Snapshot of the Field Emitted by a Nanosource Using a Photosensitive Polymer," <u>Appl. Phys. Lett.</u> 69:3306-3308 (1996)
		22	Massanell et al., "Nanowriting on Ferroelectric Surfaces with a Scanning Near-field Optical Microscope," <u>Opt. Lett.</u> 21:12-14 (1996)
		23	Madsen et al., "Optical Near-field Lithography on Hydrogen-passivated Silicon Surfaces," <u>Appl. Phys. Lett.</u> 69:544-546 (1996)
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		26	Novotny et al., "Near-field Optical Spectroscopy Based on the Field Enhancement at Laser Illuminated Metal Tips," <u>Optics and Photonics News</u> 10:24 (1999)
		27	Levi, "Progress Made in Near-field Imaging With Light From a Sharp Tip," <u>Physics Today</u> pp. 18-20 (1999)
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